

Sheet 1 of 1

FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE				ATTY. DOCKET NO. ONX-113/DIV		SERIAL NO. 10/747,875	
LIST OF PRIOR ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT David Horsley et al.			
				FILING DATE December 29, 2003		GROUP 2819	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
HFW	A	6,674,383	1/6/200	Horsley et al.	341	152	10/30/2001
HFW	B	6,386,032	5/14/2002	Lemkin et al.	73	504.02	8/1/2000
HFW	C	5,852,242	12/22/1998	Devolk et al.	73	514.17	12/4/1995
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
							YES NO
OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
EXAMINER Howard L. Williams				DATE CONSIDERED 01 April 2005			
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U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
HPW	A	5,867,302	2/2/1999	Fleming	359	291	8/7/1997
HPW	B	6,137,941	10/24/2000	Robinson	385	140	9/3/1998
HPW	C	6,296,779	10/2/2001	Clark et al.	216	66	2/22/1999
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
HPW	D	0683414	11/22/1995	Europe	G02B	26/08	
OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
HPW	E	S. Suzuki, K. Sato, S. Ueno, M. Sato, M. Esashi, "Semiconductor Capacitance-Type Accelerometer with PWM Electrostatic Servo Technique," Sensors and Actuators, A21-A23 (1990) pp. 316-319 <i>Month unknown</i>					
HPW	F	B. E. Boser, "Electronics for Micromachined Inertial Sensors", Transducers '97, 1997 International Conference on Solid-State Sensors and Actuators, Chicago, June 16-19, 1997					
HPW	G	E. K. Chan, K. Garikipati, R. W. Dutton, "Characterization of Contact Electromechanics Through Capacitance - Voltage Measurements and Simulations," Journal of Microelectromechanical Systems, Vol. 8, No. 2, June 1999					
HPW	H	C. T. Nguyen, "Micromechanical Signal Processors," Doctoral Dissertation, UC Berkeley, December, 1994					
HPW	I	L. Y. Lin, E. L. Goldstein, R. W. Tkach, "Free-Space Micromachined Optical Switches with Submillisecond Switching Time for Large Scale Optical Cross-Connects, IEEE Photonics Technology Letters, Vol. 10, No. 4, April 1998					
HPW	J	H. Toshiohi, H. Fujita, "Electrostatic Micro Torsion Mirrors for an Optical Switch Matrix," Journal of Microelectromechanical Systems, Vol. 5, No. 4, December 1996.					
HPW	K	A. Selvakumar, K. Najafi, "A High Sensitivity Z-Axis Capacitive Silicon Microaccelerometer with a Torsional Suspension," Journal of Microelectromechanical Systems, Vol. 7, No. 2, June 1998.					
HPW	L	P. Cheung, R. Horowitz, R. T. Howe, "Design, Fabrication, Position Sensing, and Control of an Electrostatically-driven Polysilicon Microactuator," IEEE Transactions on Magnetics, Vol. 32, No. 1, January 1996, pages 122-128.					
HPW	M	M. Oda, M. Shirashi, "Mechanically Operated Optical Matrix Switch," Fujitsu Scientific and Technical Journal, September, 1981.					
HPW	N	E. K. Chan, R. W. Dutton, "Electrostatic Micromechanical Actuator with Extended Range of Travel," Journal of Microelectromechanical Systems, Volume: 9 Issue: 3, Sept. 2000 Page(s): 321 -328					
HPW	O	Fedder et al., "Multimode Digital Control of a Suspended Polysilicon Microstructure", IEEE Journal of Microelectromechanical Systems, Vol. 5, No. 4, December 1996, pages 283-297					
HPW	P	Yun et al., "Surface Micromachined, Digitally force-Balanced Accelerometer with Integrated CMOS Detection Circuitry", Tech. Digest IEEE Solid-State Sensor and Actuator Workshop, June 1992, pages 126-131					
	Q	Office Action dated 10/04/2003 in prior application 10/012,668					
	R	Final Office Action dated 1/17/2003 in prior application 10/012,688					
EXAMINER <i>Edward R. Williams</i>				DATE CONSIDERED <i>26 Dec. 2004</i>			
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